

**RESPONSE UNDER 37 C.F.R. §1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2882
Docket No.: 1220.1001**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Kenichi SHIRAISHI

Serial No. 10/589,437

Group Art Unit: 2882

Confirmation No. 9870

Filed: August 1, 2007

Examiner: Mesfin T. Asfaw

For: EXPOSURE APPARATUS, SUPPLY METHOD AND RECOVERY METHOD,
EXPOSURE METHOD, AND DEVICE PRODUCING METHOD

RESPONSE AFTER FINAL

MAIL STOP AF

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

This is in response to the final Office Action mailed August 3, 2010, which has a period for response set to expire on November 3, 2010.

Reconsideration of the claims is respectfully requested. The following amendments and remarks are respectfully submitted.

Remarks begin at page 9; and

A certified translation of Japanese Patent Application No. 2004-045102 accompanies this response is attached following page 4..